

FIG. 1

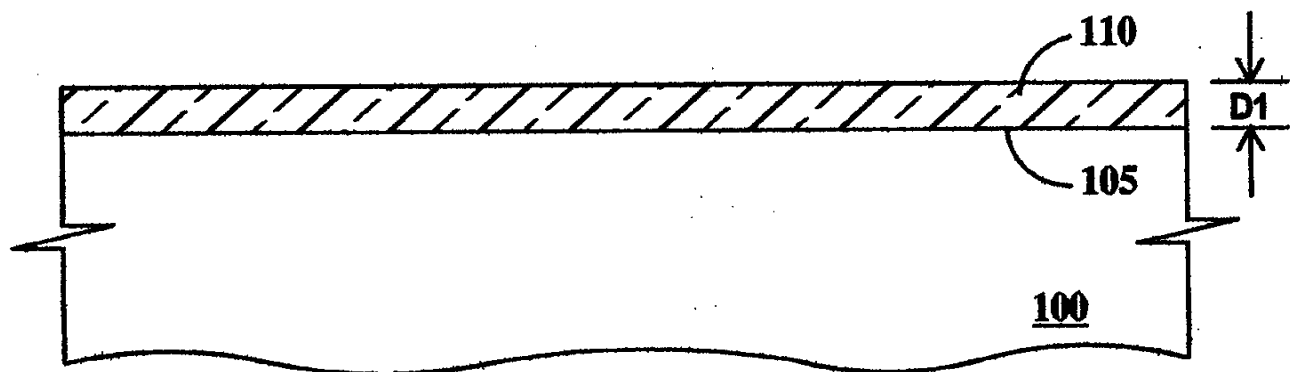


FIG. 2

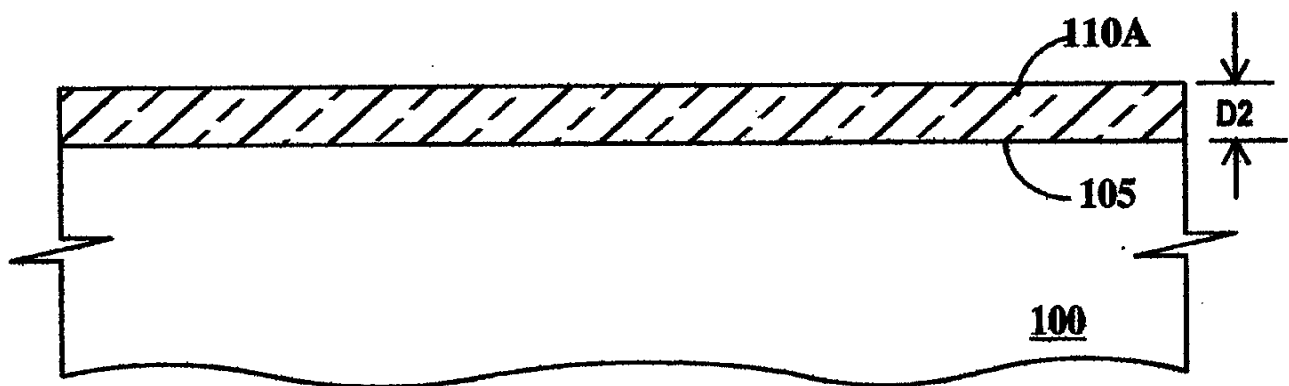


FIG. 3

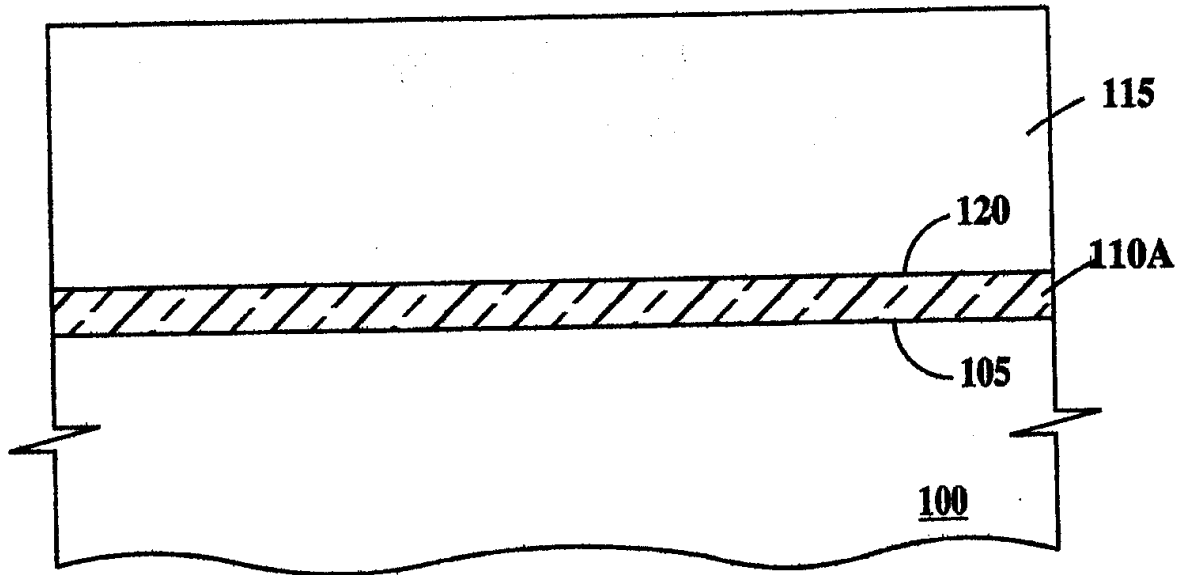


FIG. 4

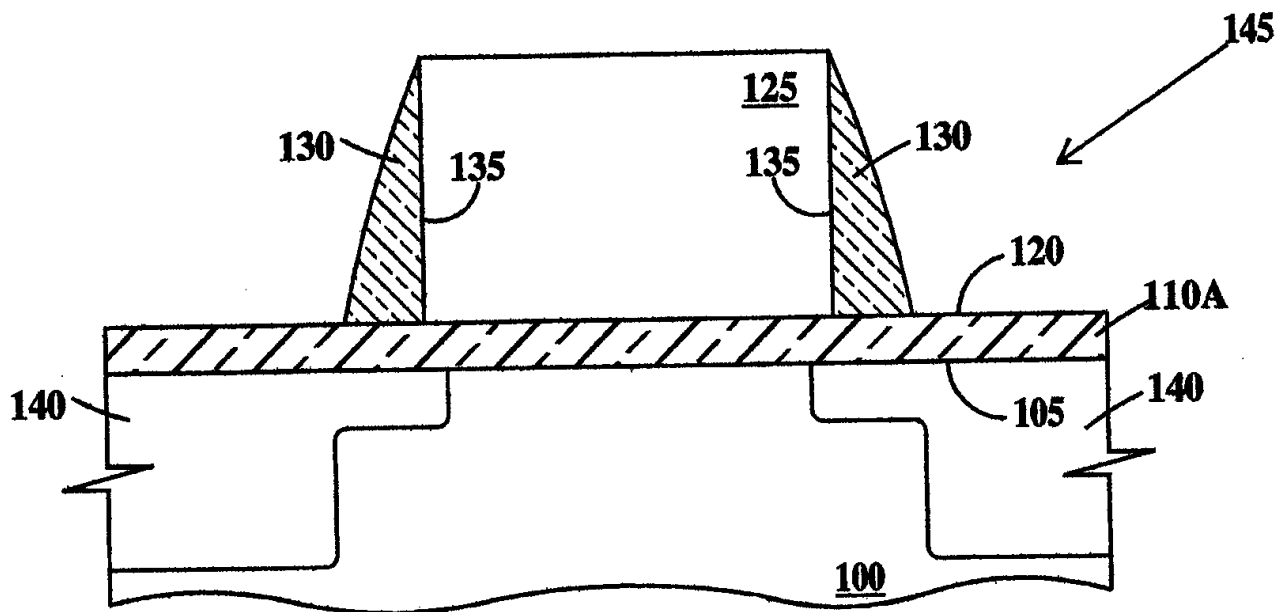


FIG. 5

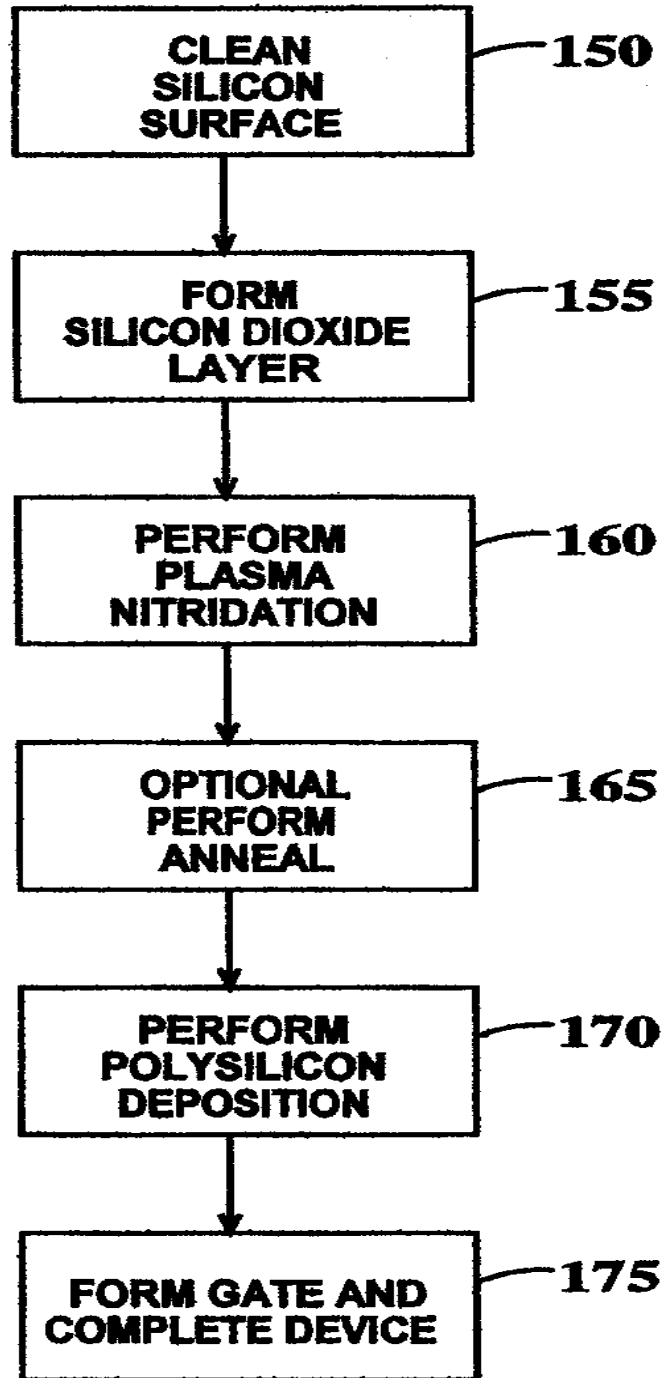
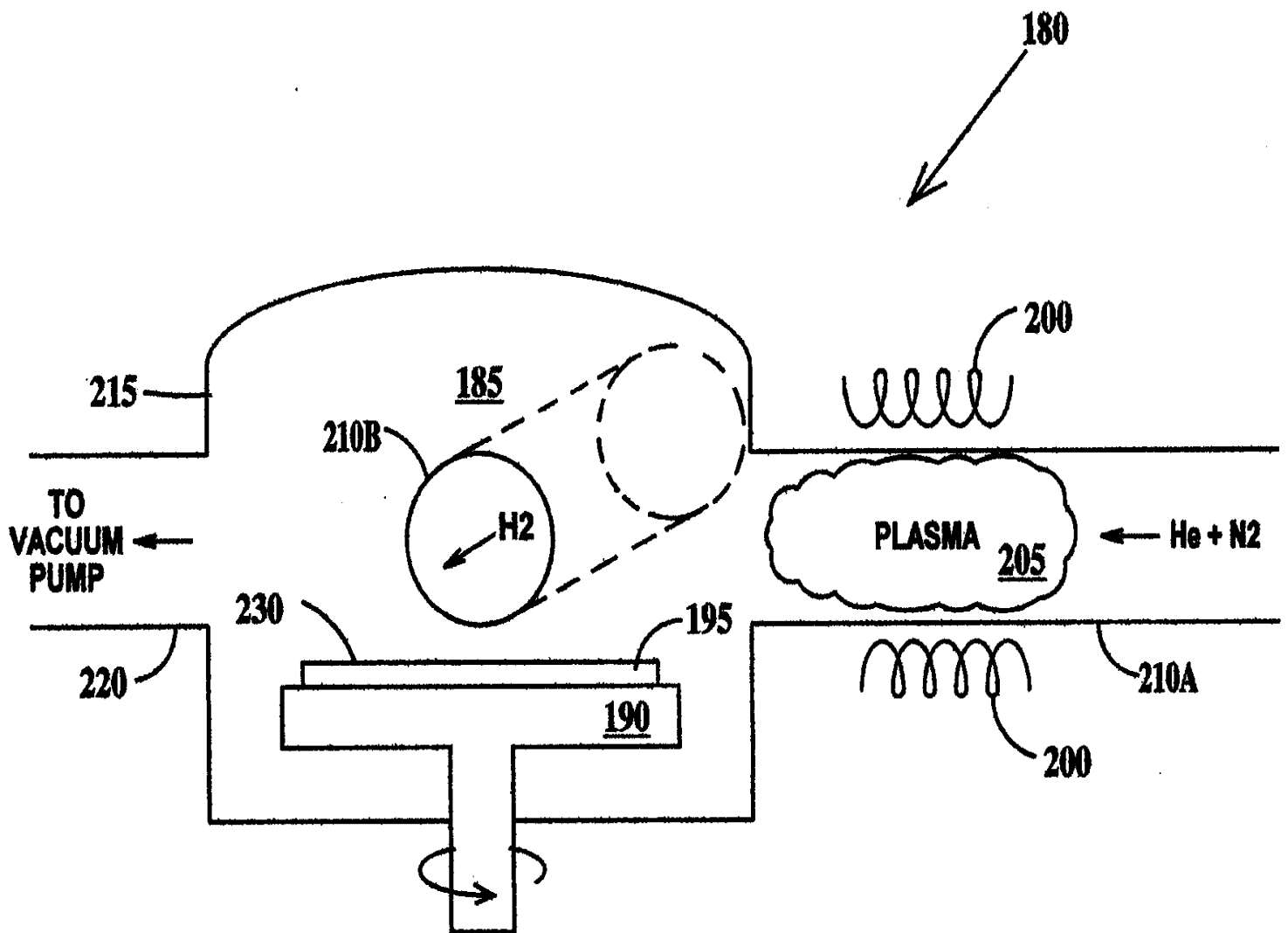


FIG. 6

**FIG. 7**

**ACROSS WAFER THICKNESS UNIFORMITY
POST REMOTE PLASMA NITRIDATION**

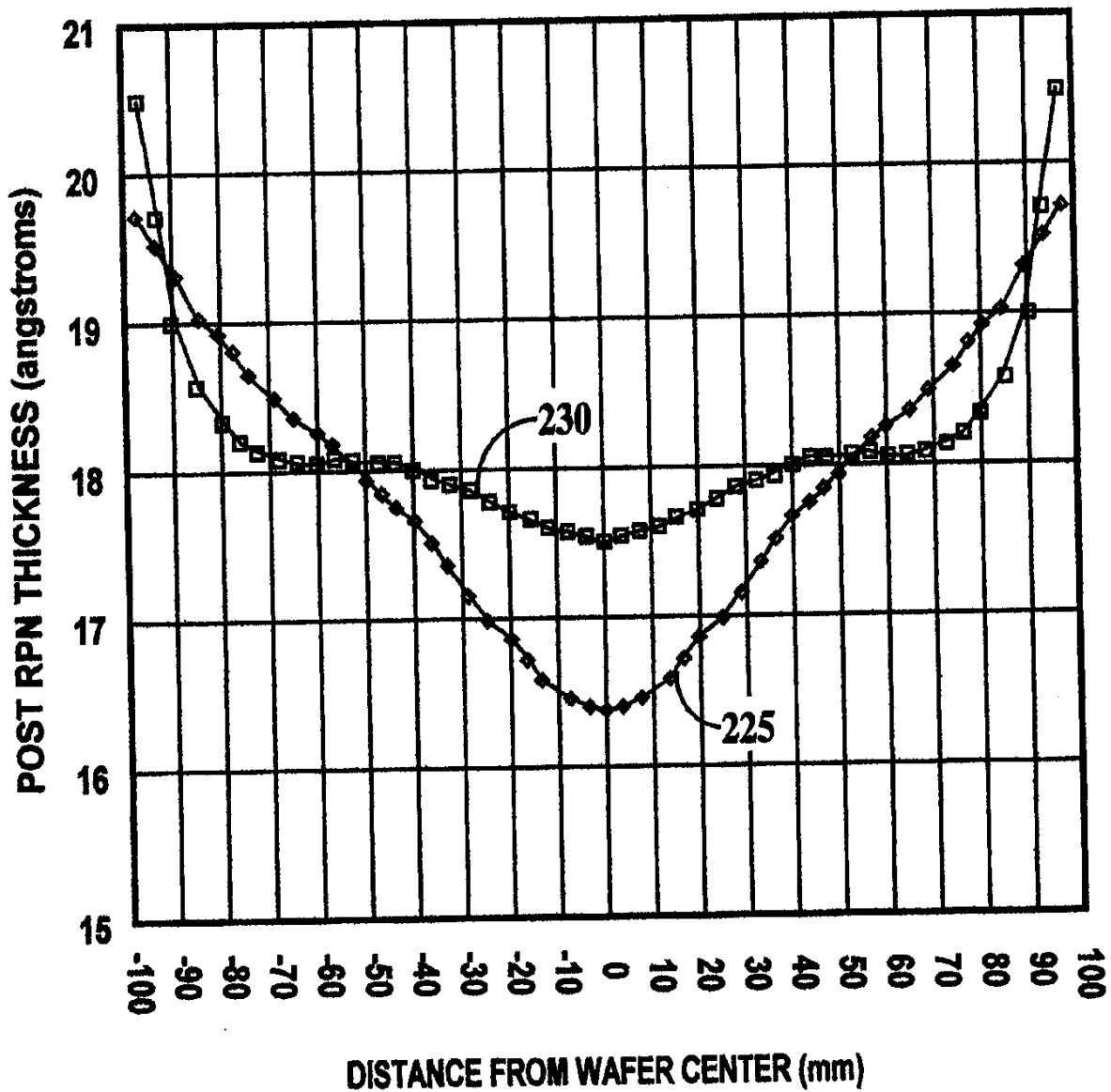


FIG. 8

**ACROSS WAFER THICKNESS UNIFORMITY
POST REMOTE PLASMA NITRIDATION
ON NATIVE OXIDE**

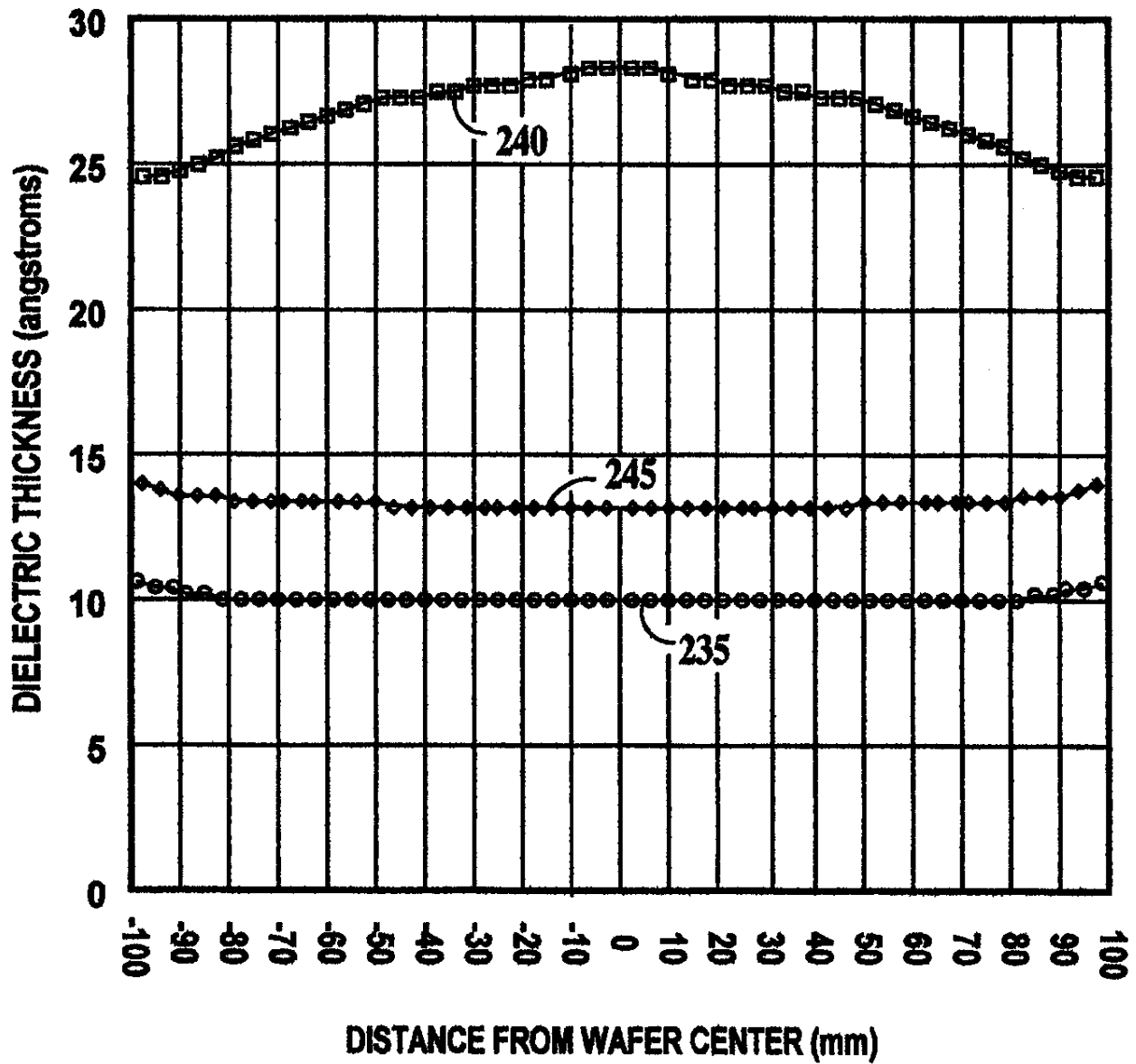


FIG. 9

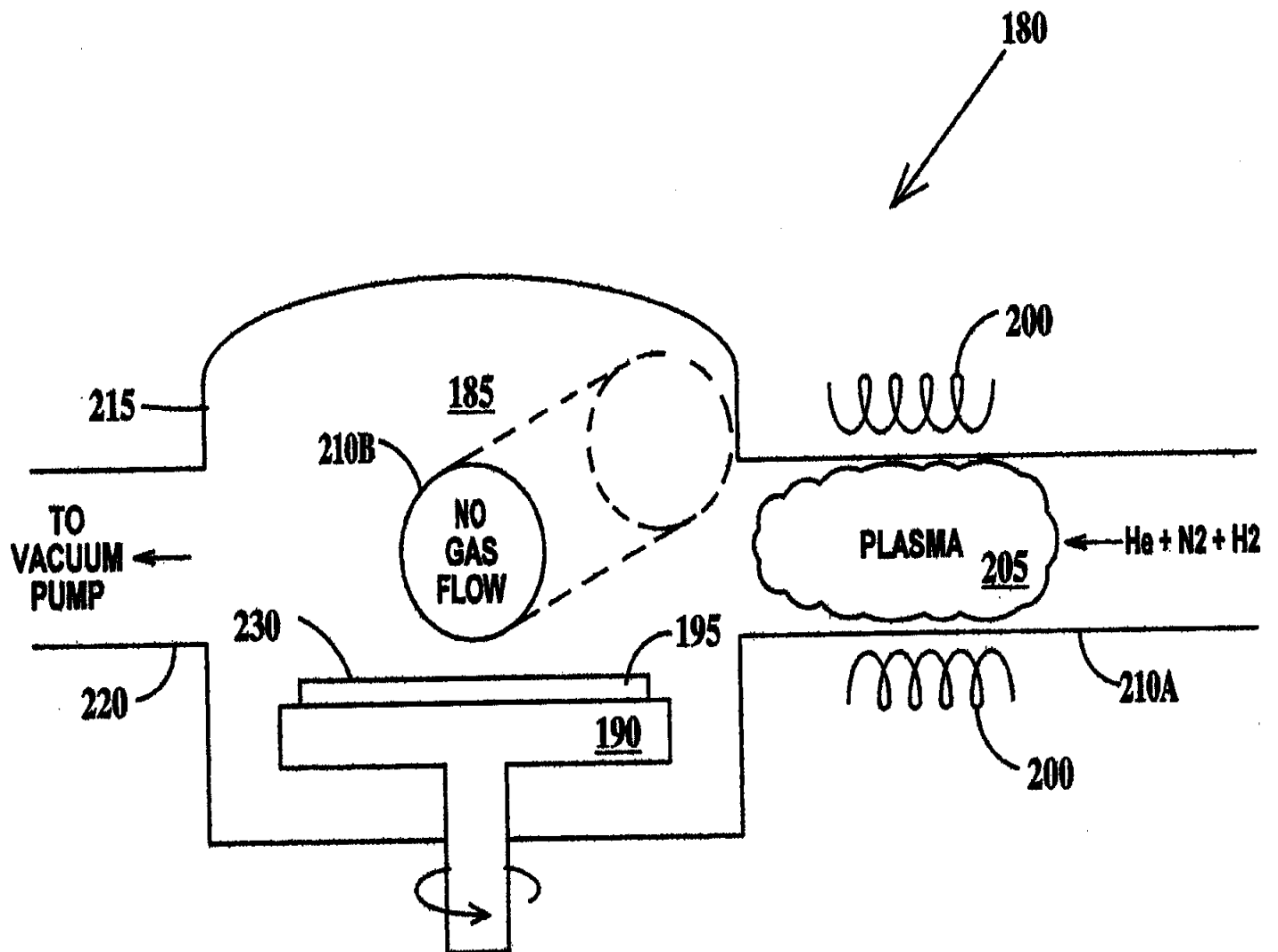


FIG. 10